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IN REPLY REFER TO:

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ULTRASONIC SPARSE IMAGING ARRAY

TO ALL WHOM IT MAY CONCERN:

BE IT KNOWN that KIM C. BENJAMIN, citizen of the United States of America, employee of the United States Government, and resident of Portsmouth, County of Newport, State of Rhode Island, has invented certain new and useful improvements entitled as set forth above, of which the following is a specification.

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PATENT TRADEMARK OFFICE

1 Attorney Docket No. 80073

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3 ULTRASONIC SPARSE IMAGING ARRAY

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5 STATEMENT OF GOVERNMENT INTEREST

6 The invention described herein may be manufactured and used
7 by and for the Government of the United States of America for
8 Governmental purposes without the payment of any royalties
9 thereon or therefor.

10

11 CROSS REFERENCE TO OTHER PATENT APPLICATIONS

12 Not applicable.

13

14 BACKGROUND OF THE INVENTION

15 1. Field of the Invention

16 The invention relates to a sparse imaging array and is
17 directed more particularly to such an array for underwater use
18 and which requires fewer transducer elements and provides a wider
19 area of focusing than prior art arrays.

20 2. Description of the Prior Art

21 Two dimensional arrays of underwater acoustic transducers
22 are known. Such arrays are made by providing relatively large
23 monolithic plates of piezo-ceramic transducer material. The
24 plates are then cut along a series of parallel lines extending in
25 a selected direction, and then cut along a series of parallel

1 lines normal to the aforementioned lines, to provide a multitude
2 of small square or rectangular block elements. A selected
3 viscoelastic material is packed into the cut-away areas to
4 decouple the block elements from each other.

5 Selected ones of the block transducer elements are then
6 wired for operation. The remaining elements provide no benefit.
7 Typically, only about 1%, or less, of the transducer elements are
8 selected for wiring. In a known array, about 250,000 block
9 elements are produced by the above-described technique, known as
10 "dice and fill". About 1700 of the formed elements are then
11 wired to become active elements. There is a need for an array in
12 which such waste of materials is avoided and related costs are
13 reduced.

14 Further, it is beneficial to place the active elements in
15 positions selected with precision. However, given that the
16 active elements of the above-described known array necessarily
17 reside in areas defined by criss-crossing lines, the active
18 element which is closest to the desired location is used in
19 practice. In short, the active elements are located
20 approximately where wanted, but not usually precisely where
21 wanted. There is a need for an array in which the active
22 elements are placed precisely where wanted.

23 Still further, the spatial response of each rectangular
24 block element is perturbed by non-resonant lateral waves
25 traveling in the plane of the array. Such waves occur at a

1 critical angle based on the relative sound speeds of the array
2 material and the surrounding fluid, typically sea water. Passing
3 through the piezo ceramic element, such lateral waves cause an
4 out of phase voltage with respect to a desired mode voltage and
5 essentially limit the element beam width. There is a need for an
6 array with improved element beamwidth.

8 SUMMARY OF THE INVENTION

9 An object of the invention is, therefore, to provide an
10 ultrasonic sparse imaging array for underwater use, the array
11 including a selected number of active transducer elements with no
12 inactive transducer elements.

13 A further object of the invention is to provide such an
14 array in which each transducer element is located precisely where
15 desired on a substrate.

16 A still further object of the invention is to provide such
17 an array having elements which provide a wider beam width to
18 provide the array with a larger field of view.

19 A still further object of the invention is to provide a low
20 cost method for making an ultrasonic sparse imaging array having
21 the attributes noted immediately above.

22 With the above and other objects in view, a feature of the
23 present invention is the provision of an ultrasonic sparse
24 imaging array comprising a backing substrate of highly
25 acoustically absorptive material, a multiplicity of holes

1 extending through the substrate, a multiplicity of adhesive
2 sheets having selectively conductive regions, the sheets each
3 being fixed to a first side of the backing substrate and disposed
4 over a first end of one of the holes, to provide a mechanical and
5 electrical connection between the substrate and a multiplicity of
6 transducer elements within the array. Plano-convex shaped
7 transducer elements, each having a wide acoustic beamwidth, are
8 respectively disposed on each of the sheets. Each of the sheets
9 constitutes a positive electrode. A plating is fixed to the
10 first side of the substrate, covering each of the transducer
11 elements and constitutes a negative electrode. A conductive pin
12 is disposed in each of the holes, the pins each being provided
13 with an annular disc portion which closes second ends of the
14 holes. A conductive epoxy fills each of the holes between the
15 pin disc and the sheet. A power source is provided and is in
16 electrical communication with the plating.

17 In accordance with a further feature of the invention, there
18 is provided a method for making an ultrasonic sparse imaging
19 array, the method comprising the steps of providing a substrate
20 of highly absorptive material, drilling a multiplicity of holes
21 through the substrate in a selected pattern, injecting conductive
22 epoxy into the holes, inserting conductive pins, one each, into
23 the holes, the pins each having an annular disc portion which is
24 brought into engagement with the substrate undersurface to close
25 off undersurface ends of the holes, removing epoxy overflowed

1 from the holes from an undersurface and an upper surface of the
2 substrate, fixing a sheet of dry film adhesive with selectively
3 conductive regions, and comprising a positive electrode, on the
4 upper surface of the substrate, and fixing a generally plano-
5 convex shaped transducer element on each of the sheets, disposing
6 a plating on the upper surface of the substrate, the plating
7 covering the transducer elements and comprising a negative
8 electrode, and providing connections on the plating for placing
9 the plating in electrical communication with a power source.

10 The above and other features of the invention, including
11 various novel details of construction and combinations of parts
12 and method steps, will now be more particularly described with
13 reference to the accompanying drawings and pointed out in the
14 claims. It will be understood that the particular device and
15 method embodying the invention are shown by way of illustration
16 only and not as limitations of the invention. The principles and
17 features of this invention may be employed in various and
18 numerous embodiments without departing from the scope of the
19 invention.

20
21 BRIEF DESCRIPTION OF THE DRAWINGS

22 Reference is made to the accompanying drawings in which is
23 shown an illustrative embodiment of the invention, from which its
24 novel features and advantages will be apparent, wherein

1 corresponding reference characters indicate corresponding parts
2 throughout the several views of the drawings and wherein:

3 FIG. 1 is a perspective view of one form of an array
4 illustrative of an embodiment of the invention;

5 FIG. 2 is a sectional view taken along line 2-2 of FIG. 1;

6 FIG. 3 is a bottom plan view of one form of a sheet portion
7 of the transducer assembly shown in FIG. 2; and

8 FIG. 4 is a cross section taken along line IV-IV of FIG. 3.

9
10 DESCRIPTION OF THE PREFERRED EMBODIMENT

11 Referring to FIG. 1, it will be seen that the illustrative
12 array 10 includes a substrate, or array backing, 12 in a sheet
13 form. The substrate 12 preferably is of a material which is
14 highly absorptive at ultrasonic frequencies, such as tungsten-
15 epoxy composite. The substrate can be planar, or curved in one
16 or two directions. In the substrate 12 are disposed a
17 multiplicity of holes 14 (FIG. 2) extending therethrough. The
18 holes 14 are disposed at the precise locations where the presence
19 of an active transducer element is deemed desirable. The holes
20 14 are packed with an electrically conductive epoxy 16.

21 A lower positive electrode sheet 18 is disposed on an upper
22 surface 20 of the substrate 12. The sheet 18 may be an adhesive
23 film with selectively conductive regions 18a(FIG. 3).A plano-
24 convex shaped transducer element 24 is placed on each of the
25 sheets 18, with a planar surface 21 of the transducer element 24

1 resting on one of the sheets 18. Covering an upper end 22 of
2 each of the holes 14, the sheet 18 provides mechanical and
3 electrical connectivity between the substrate 12 and transducer
4 elements 24. The plano-convex shaped transducer elements 24
5 preferably are comprised of a piezoelectric material, such as
6 solid piezoceramic, piezoceramic-polymer composite, or
7 piezoelectric elastomer (i.e., polyvinylidene fluoride (PVDF)).

8 An upper negative electrode plating 26 is applied to the
9 substrate upper surface 20 and over the transducer elements 24.
10 The upper plating 26 may be of copper plating or a conductive
11 epoxy. If copper, or other suitable metal, such as chromium, the
12 upper plating 26 may be applied by vacuum deposition.

13 A conductive pin 28 is disposed in each of the holes 14.
14 The pins 18 are of about .020 inch in diameter and preferably are
15 of copper with tin plating. The pins 28 are each provided with a
16 disc portion 30 which engages an undersurface 32 of the substrate
17 12. An upper portion 34 of the pin 28 is embedded in the
18 aforementioned epoxy 16. A lower portion 36 of the pin 28
19 extends axially outwardly from the disc portion 30 and the
20 substrate undersurface 32. By a connection 38 an electrically
21 conductive wire 40 extends from a free end of the pin lower
22 portion 36 and is, in turn, connectable to signal conditioning
23 electronics and/or a computer with display, or the like (not
24 shown). The connection 38 may be an interference fit socket-type
25 (shown in FIG. 2), a wire wrap type, or simply a soldered

1 connection. The upper negative electrode plating 26 is
2 connected, as by wiring 46 to a power source 48.

3 Referring to FIG. 3, it will be seen that the sheet, or
4 lower positive electrode, 18 may be apodised to include radially-
5 extending electrically conductive portions 18a and non conductive
6 portions 18b. Such a configuration, in combination with the
7 plano-convex shaped transducers 24, serves to broaden the spatial
8 acceptance angle and widen the field from which acoustic activity
9 is received.

10 The above described array preferably is made as follows:

11 The substrate 12 is provided in a desired configuration
12 which may include planar, or singly or doubly curved surfaces.
13 The substrate 12 may be constructed in one piece or in sections.
14 Holes 14 are drilled through the substrate 12 precisely where
15 desired, using known Numerical Control laser drilling. The
16 conductive epoxy 16 is then injected into the holes 14. The
17 conductive pins 28 are then inserted into the holes 14 until the
18 disc portions 30 of the pins 28 engage the substrate undersurface
19 32 to close off undersurface ends 44 of the holes 14. Any epoxy
20 overflowing onto the substrate surfaces 20, 32 is removed to
21 provide clean substrate surfaces 20, 32. The conductive epoxy 12
22 is allowed to cure.

23 The sheets 18, comprising the lower positive electrodes are
24 fixed each to the upper surface 20 of the substrate 12 and over a
25 hole 14 to close off the hole upper ends 22. The generally

1 plano-convex shaped transducer elements 24 are then each fixed to
2 one of the sheets 18, using known "pick and place" technology.

3 The plating 26, serving as the upper negative electrode, is
4 applied to the substrate upper surface 20 so as to cover the
5 substrate upper surface 20 and the transducer elements 24.

6 Finally, the plating 26 is placed in electrical
7 communication with a power source 48 and the pins 28 are placed
8 in electrical communication with signal enhancing electronics,
9 and/or a computer, display, and the like, by the connection 38.
10 FIG. 4 illustrates a cross-section of the transducer assembly
11 shown in FIG. 3.

12 There is thus provided an array in which only the number of
13 transducer elements needed are used in the apparatus. There is
14 further provided an array in which the transducer elements are
15 disposed precisely where they are wanted. There is still further
16 provided an array having a wider field of view over which the
17 array can focus, by virtue of the plano-convex shaped transducer
18 elements and by virtue of their being placed so as not to shield
19 one another. Finally, there is provided a method for making a
20 sparse imaging array, that is compatible with the current "pick
21 and place" technology, and which reduces greatly the amount of
22 array material required, and which improves performance.

23 It will be understood that many additional changes in the
24 details, materials, steps and arrangement of parts, which have
25 been herein described and illustrated in order to explain the

1 nature of the invention, may be made by those skilled in the art
2 within the principles and scope of the invention

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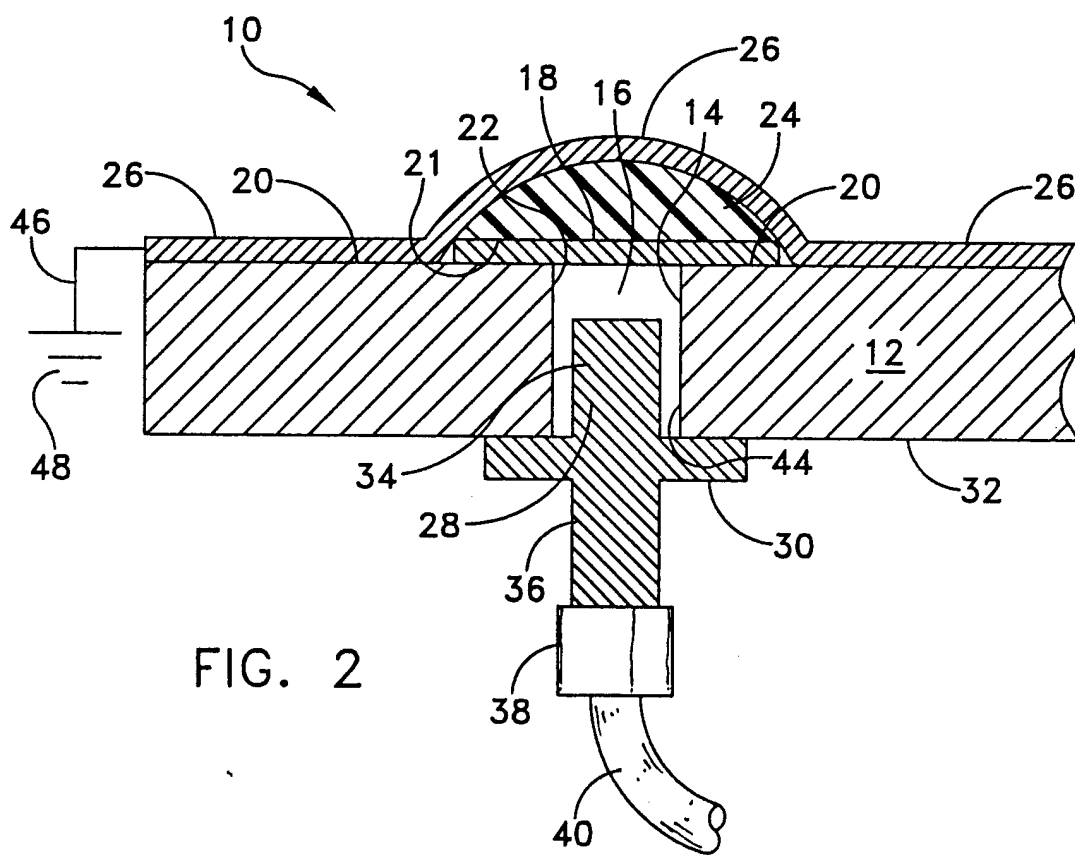
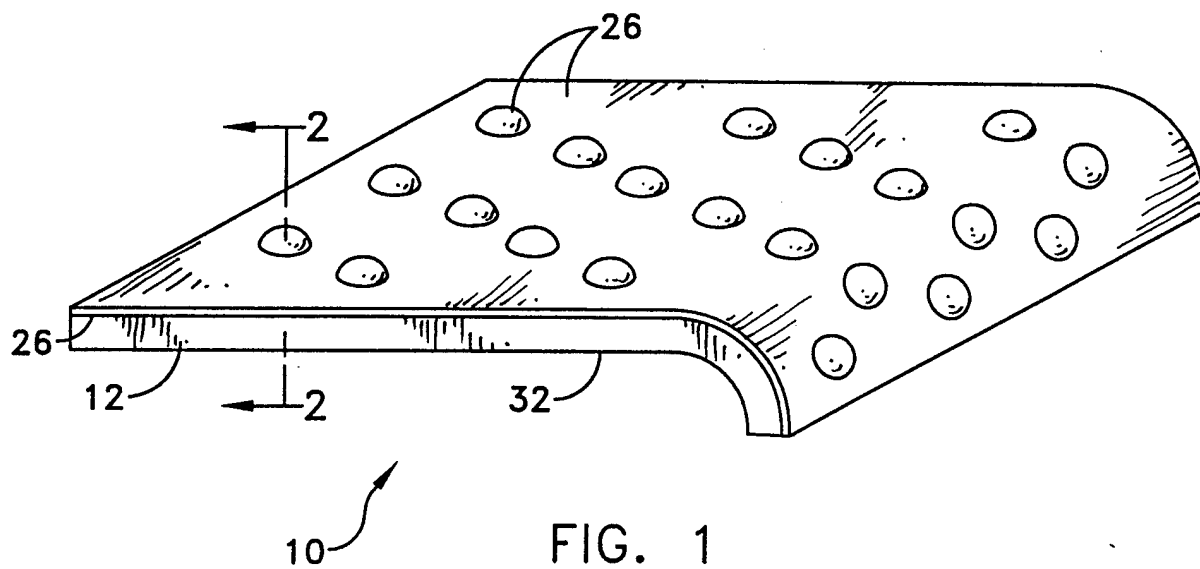
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3 ULTRASONIC SPARSE IMAGING ARRAY

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5 ABSTRACT OF THE DISCLOSURE

6 An ultrasonic sparse imaging array includes a substrate of
7 an acoustically absorptive material, through which extend a
8 multiplicity of holes. Adhesive sheets, having selectively
9 conductive regions, are fixed to a first side of the substrate,
10 and are each disposed over a first end of one of the holes.
11 Plano-convex shaped transducer elements, having a wide acoustic
12 field of view, are disposed on each of the sheets, each of the
13 sheets serving as a positive electrode and providing a mechanical
14 and electrical connection between the substrate and a
15 multiplicity of transducer elements. Plating is fixed to the
16 first side of the substrate and covers each of the transducer
17 elements and comprises a negative electrode. A conductive epoxy
18 fills each of the holes and a power source is in electrical
19 communication with the negative electrode.



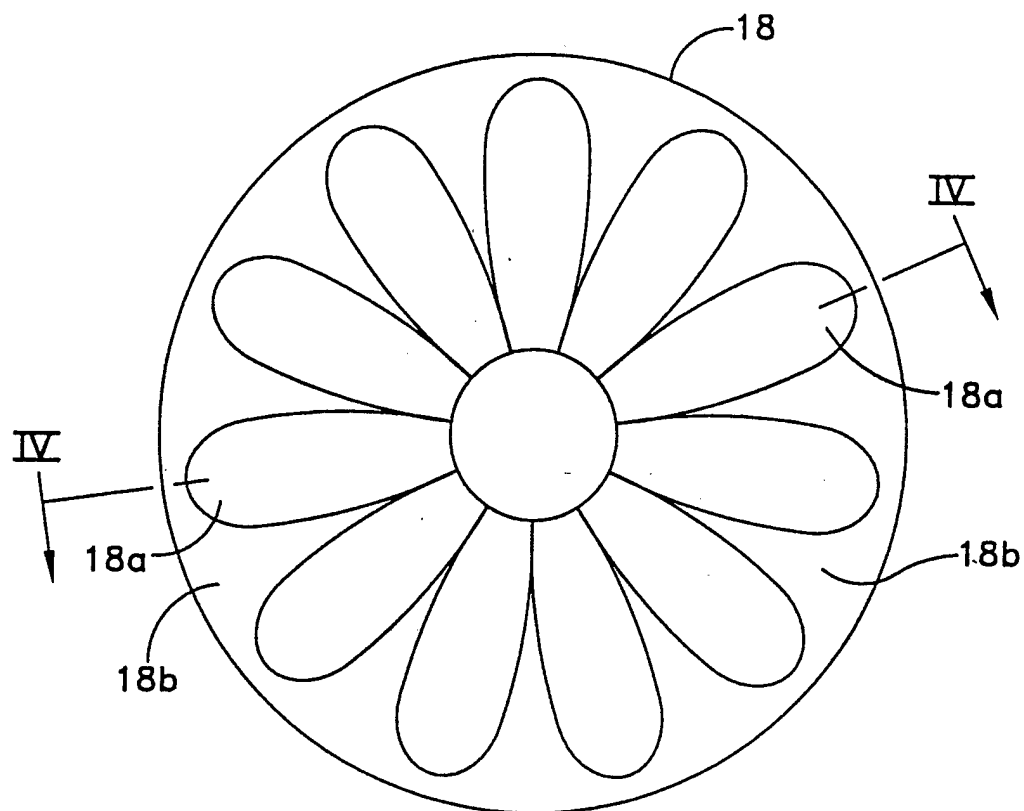


FIG. 3

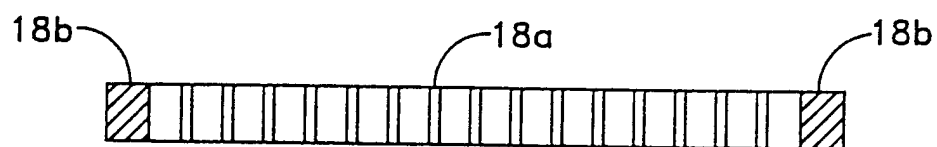


FIG. 4